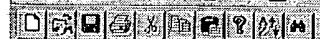


L Number	Hits	Search Text	DB	Time stamp
1	3134	hirooka	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/08/20 15:56
2	34	hirooka and resistivity	USPÄT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/08/20 15:57
-	9	"193758"	USPÄT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/10/08 12:20
-	2760	hirooka	USPÄT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/08/20 15:56
-	30	hirooka and resistivity	USPÄT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/08/20 15:56
-	1	10-193758	USPÄT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/10/08 12:23
-	5170	alumina with titanium with carbide	USPÄT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 14:19
-	691	alumina near titanium near carbide	USPÄT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 11:11
-	115	alumina near titanium near carbide and clean\$3	USPÄT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 11:11
-	19	alumina near titanium near carbide and clean\$3 and resistivity	USPÄT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 12:57
-	8	((("5,336,371") or ("5,693,148") or ("5,873,380") or ("6,167,583"))).PN.	USPÄT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 11:36
-	4	((("5,336,371") or ("5,693,148") or ("5,873,380") or ("6,167,583"))).PN.	USPÄT	2004/04/06 12:34
-	0	((("5,336,371") or ("5,693,148") or ("5,873,380") or ("6,167,583"))).PN.) and alumina near titanium near carbide	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 12:34
-	0	((("5,336,371") or ("5,693,148") or ("5,873,380") or ("6,167,583"))).PN.) and alumina near (titanium carbide)	USPÄT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 12:34

-	0	((("5,336,371") or ("5,693,148") or ("5,873,380") or ("6,167,583")).PN.) and alumina with (titanium carbide)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 12:35
-	1	((("5,336,371") or ("5,693,148") or ("5,873,380") or ("6,167,583")).PN.) and (alumina titanium carbide)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 12:35
-	31	alumina near titanium near carbide and omega	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 12:58
-	609	alumina near titanium near carbide not memory	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 12:58
-	40	alumina near titanium near carbide not memory and electronic	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 12:58
-	83	soak with \$5pure with water	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 14:13
-	12	soak with \$5pure with water with wafer	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 14:13
-	12	soak with \$5pure with water with wafer and (water alumina titanium carbide)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 14:17
-	0	soak with ultrapure with water with wafer	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 14:18
-	0	soak with omega with water with wafer	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 14:19
-	0	soak with omega with water	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 14:19
-	0	alumina with titanium with carbide with soak	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 14:27
-	0	alumina with titanium with carbide with soak\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/06 14:28



- ☐ Drafts
- ☐ Pending
- ☐ Active
- ☐ Failed
- ☐ Saved
- ☐ Favorites
- ☒ Tagged (7)
- ☐ UDC
- ☐ Queue
- ☐ Trash

 USPAT:US-PGPUB:EPO:JPO:DERWENT:IBM_TDB

☒ Plurals

 Default operator:
☒ Highlight all hit terms initially

	U	1	Document ID	Issue Dat	Pages	Title	Current OR	Current XR	Retr	Inv
1	<input type="checkbox"/>	<input type="checkbox"/>	US 5654850 A	19970805	20	Carbon overcoat with electrically conductive	360/235.2	360/122;		Ganapath.
2	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5741403 A	19980421	11	Ceramic substrates and magnetic data storage c	204/192.2	360/235.4; 204/192.1;		Srinivas Tenhover.
3	<input type="checkbox"/>	<input type="checkbox"/>	US 5616426 A	19970401	11	Ceramic substrate with silicon carbide smoothi	428/688	204/192.15 427/577;		A. et al Tenhover.
4	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5336371 A	19940809	6	Semiconductor wafer cleaning and rinsing te	134/34	428/408; 257/E21.22		A. et al Chung, B
5	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5693148 A	19971202	12	Process for brush cleaning	134/18	8; 134/1.3;		al. Simmons,
6	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5873380 A	19990223	15	Wafer cleaning apparatus	134/102.1	134/29; 134/153;		et al. Kanno, I
7	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6167583 B1	20010102	12	Double side cleaning apparatus for semicondu	15/77	134/902 134/172;		Miyashit. et al.
								134/199;		